

Radiation hardness of 3D pixel detectors up to $2e16 n_{eq}/cm^2$

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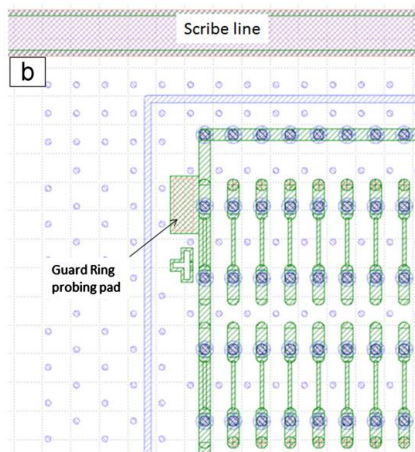
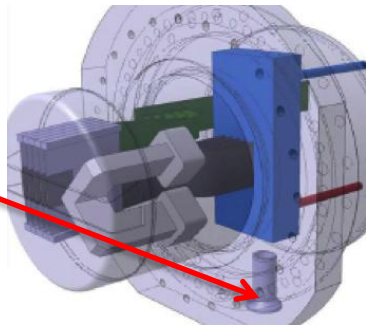
27th RD50 Workshop, CERN, 2-4 Dec 2015



Today's 3D Pixel Detectors



- ATLAS IBL
 - 25% 3D detectors
 - Installed and running!
→ 3D in action
- ATLAS Forward Proton (AFP)
 - Successful 3D sensor qualification
 - 3D module production on-going at IFAE
 - To be installed early next year
- Properties of IBL/AFP 3D pixel detectors
 - 230 μm thick sensors by CNM and FBK
 - FEI4s: 50x250 μm , 67 μm inter-el. spacing
 - FEI3s (tests): 50x400 μm , 71 μm inter-el. spacing
 - Radiation hardness up to $5\text{e}15\text{ n}_{\text{eq}}/\text{cm}^2$ established
 - >97% hit efficiency above 160 V
(conservative! In fact for many devices already from 120 V)
 - Low power dissipation: 10-15 mW/cm^2 at $T=-15\text{ }^\circ\text{C}$



New Developments for HL-LHC

- High-Luminosity LHC (HL-LHC) upgrade 2024
 - increased occupancy
 - unprecedented radiation levels ($1-2 \times 10^{16} n_{eq}/cm^2$ innermost pixels)

- Development of new pixel sensors and front-end (RD53)

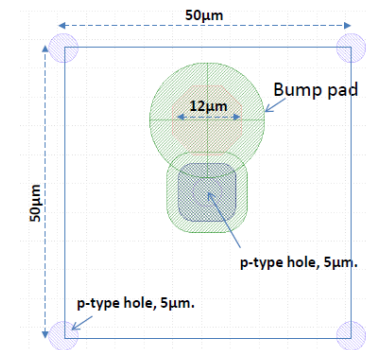
- Reduced pixel size: $50 \times 50 \mu m^2$ or $25 \times 100 \mu m^2$
- Reduced 3D inter-electrode distance
- Possibly reduced thickness (100-150 μm)
- Reduced threshold $\sim 1000e$ (in-time)

- Strategy for 3D HL-LHC R&D

- New generation of 3D productions under way
 - But takes time (~ 1 year)
 - First small-pixel run almost finished now
 - First very thin (50 μm) single-sided CNM run ready

- Explore the limits of existing 3D technology and devices (IBL/AFP generation)

- Neutron irradiated FEI3 up to $2e16 n_{eq}/cm^2$ → this talk
- Proton irradiated FEI4 up to $\sim 1e16 n_{eq}/cm^2$ → next talk (I. Lopez)
- Efficiency of 50 μm pitch under high angle → I. Lopez, 26th RD50 Workshop, Santander, 2015



G. Pellegrini, CNM

Layout	50x50 1E	25x100 1E	25x100 2E
El. Dist. L	35 μm	52 μm	28 μm

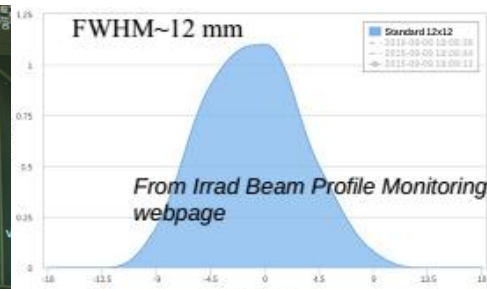
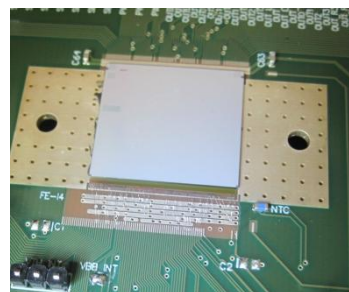
cf. FE-I4: L=67 μm

HL-LHC Studies: Irradiation Campaigns

• PS IRRAD 23 GeV p (Nov 2014 + Fall 2015)

- FEI4 3D pixel detectors
 - Non-uniform (12 mm FWHM beam)
→ difficult for IV/power dissipation studies
 - In 2014 reached $9e15$ n_{eq}/cm^2
 - Beam tests successful → see I. Lopez' talk
 - Now further irradiation to $2e16$ n_{eq}/cm^2 finished
 - Radiation hardness of FEI4 after p irradiation above $1e16$ n_{eq}/cm^2 not clear
- make complementary studies with neutron irradiation for more uniform irradiation and to reach higher fluence

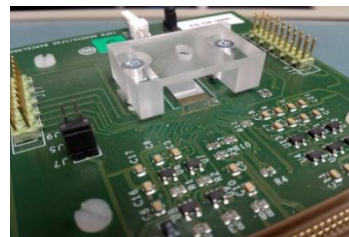
Thanks to Federico Ravotti for irradiation!



• JSI Ljubljana n (May 2015)

- FEI4 has problem of Ta activation
→ take FEI3
- Also have plenty FEI3s from CNM IBL wafers with great V_{BD} of 300 V
- Uniform irradiation good for IV/power dissipation study
- Fluences:
 $5e15$, $1e16$ (2x), $1.5e16$ (2x), $2e16$ n_{eq}/cm^2
- Assembled at IFAE (bump- and wire-bond + gluing)

Thanks to Igor Mandic, Vladimir Cindro for irradiation and AIDA2020 support!

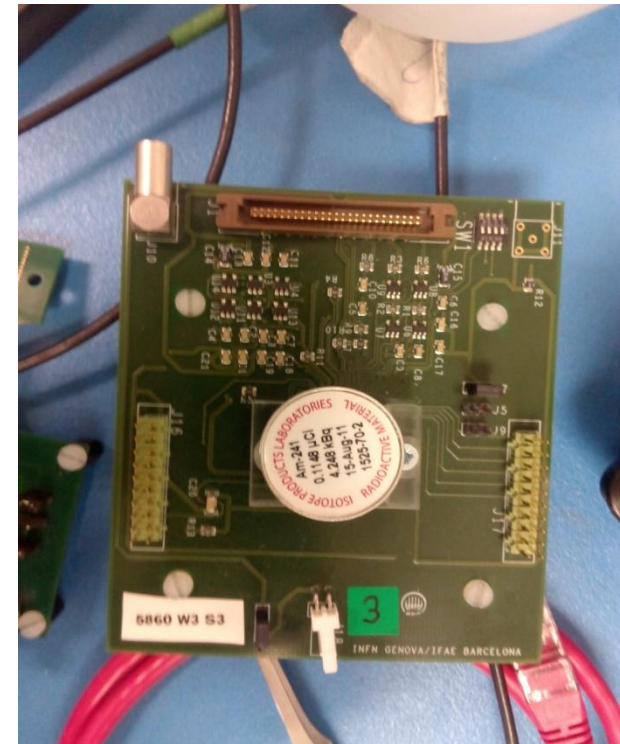


First time 3D pixel detectors irradiated to HL-LHC fluences!

FEI3 Charge Collection Studies

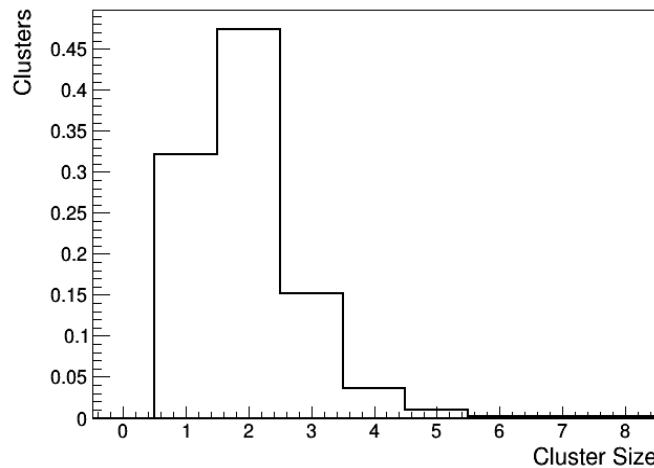
- Sr 90 source (not collimated)
- External scintillator trigger
- USBpix readout system
- Tuning
 - Relatively high threshold of FEI3: compared 2.5, 3 and 3.5 ke
 - 30 ToT at 10 ke
 - Performed ToT to Q calibration with FEI3 charge injection circuit
- Measurement temperature
 - Climate chamber set to -30 C
 - On-sensor $T \sim -25$ C: benchmark T for ATLAS ITk (see slides later)

Measurements by D. Vazquez

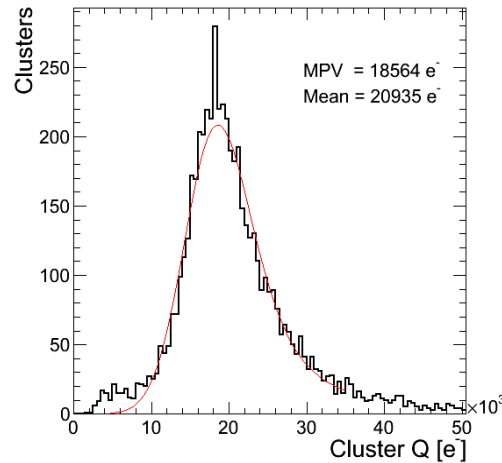


Charge Collection Studies – Unirradiated

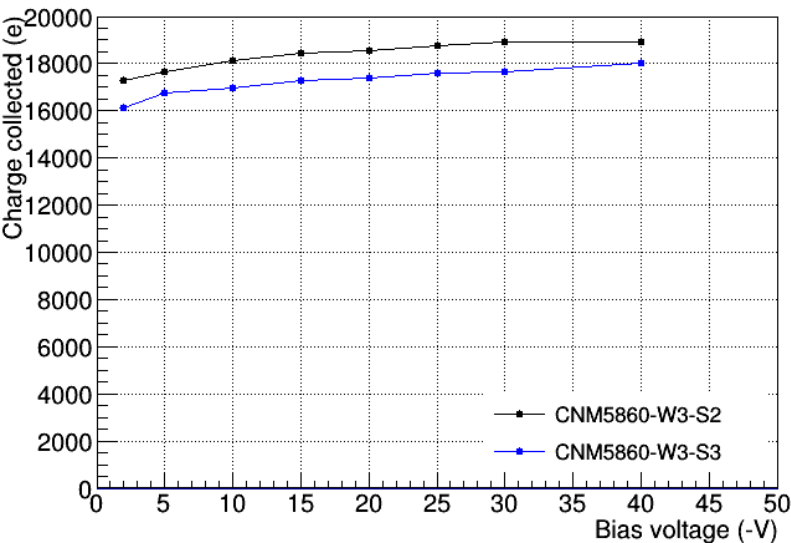
Cluster Size CNM-5860-w3-s2 3000e 30at10ke 20V



CNM-5860-w3-s2 3000e 30at10ke 20V



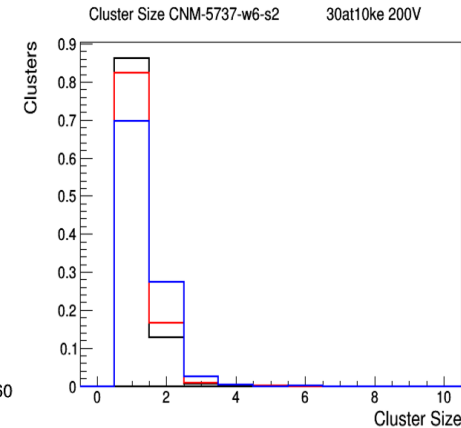
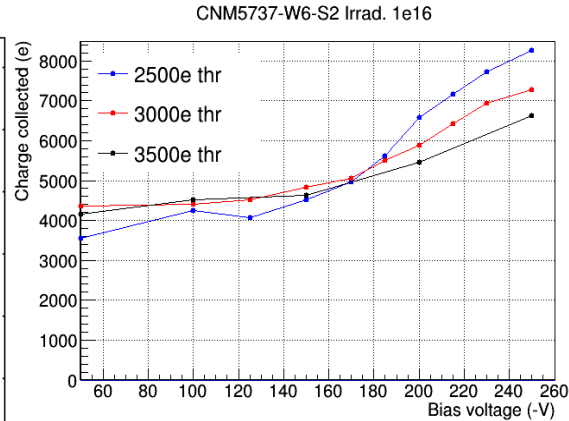
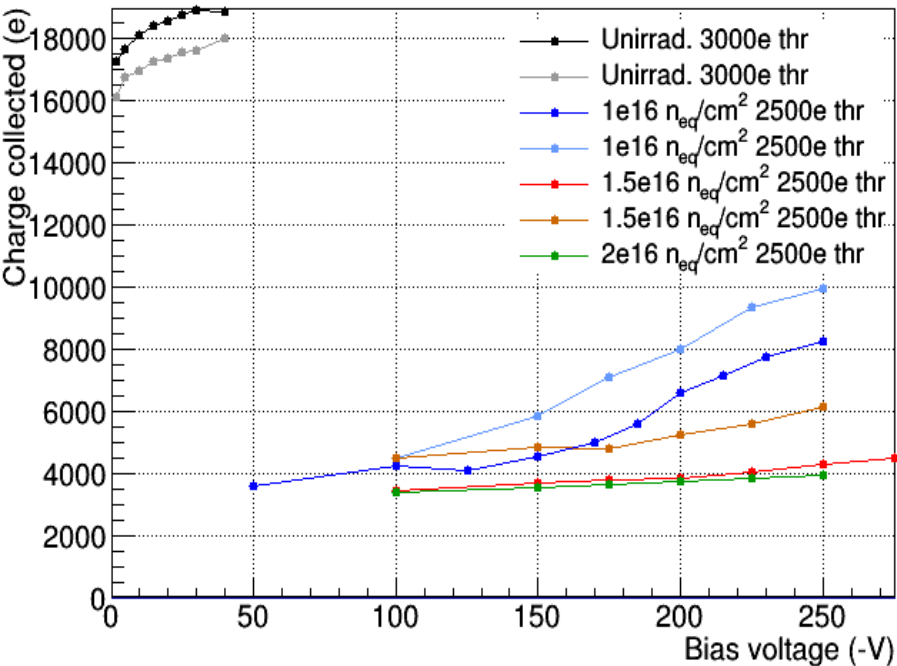
Non irradiated devices at 3000e threshold



- Cluster size ~ 2 (not collimated)
- Landau*Gauss shape
- MPV plateau ~ 18 ke
 - In agreement with expected 17 ke (for 73 e-h pairs/ μm and 230 μm)

Charge Collection Studies – Irradiated

Comparison non irradiated vs irradiated

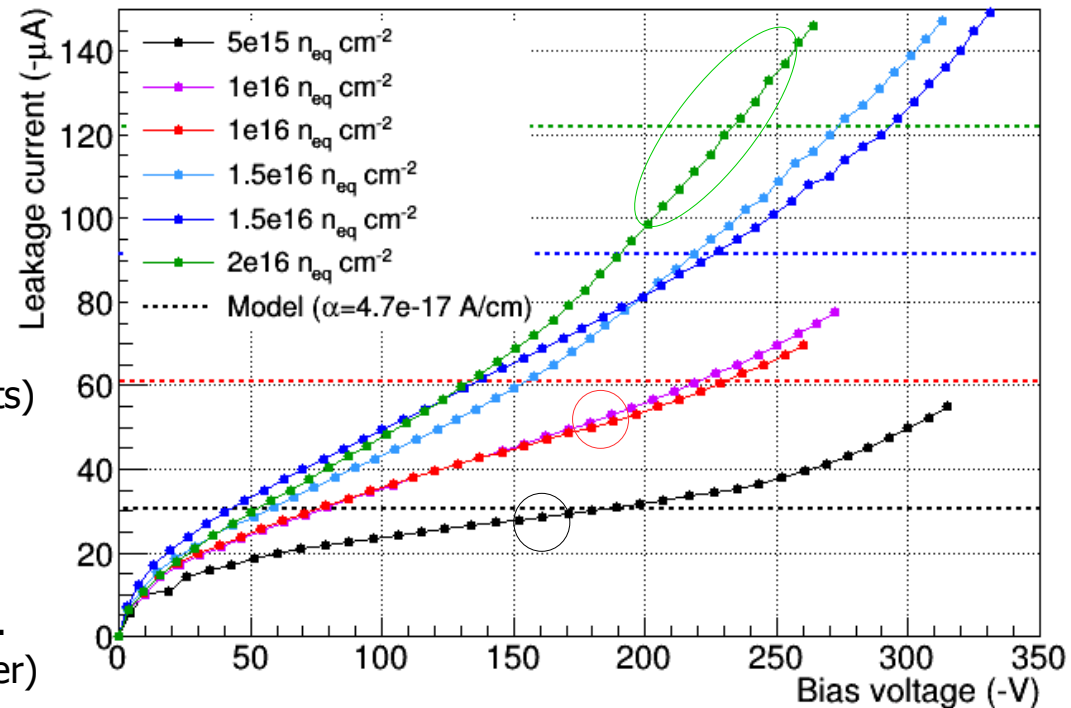


- **Threshold dependence:** Charge and hit loss at higher thresholds
- Even with FEI3 threshold of 2.5 ke and 71 μm 3D inter-electrode distance: **$Q \sim 4 \text{ ke}$** (for 230 μm) and **$\text{CCE} \sim 21\%$** at 200 V for $2e16 \text{ n}_{\text{eq}}/\text{cm}^2$!
 - Cf. to strips (no threshold, 57 μm el. dist.): $\text{CCE} \sim 30\text{-}35\%$ at 200 V [4,5]
- **Expect improvement** for RD53 threshold of 1 ke and 35 μm 3D inter-electrode distance
 - Partly compensated for total charge if going thinner for normal incidence

FEI3 Leakage Current: Fluence Dependence

Measurements by D. Vazquez

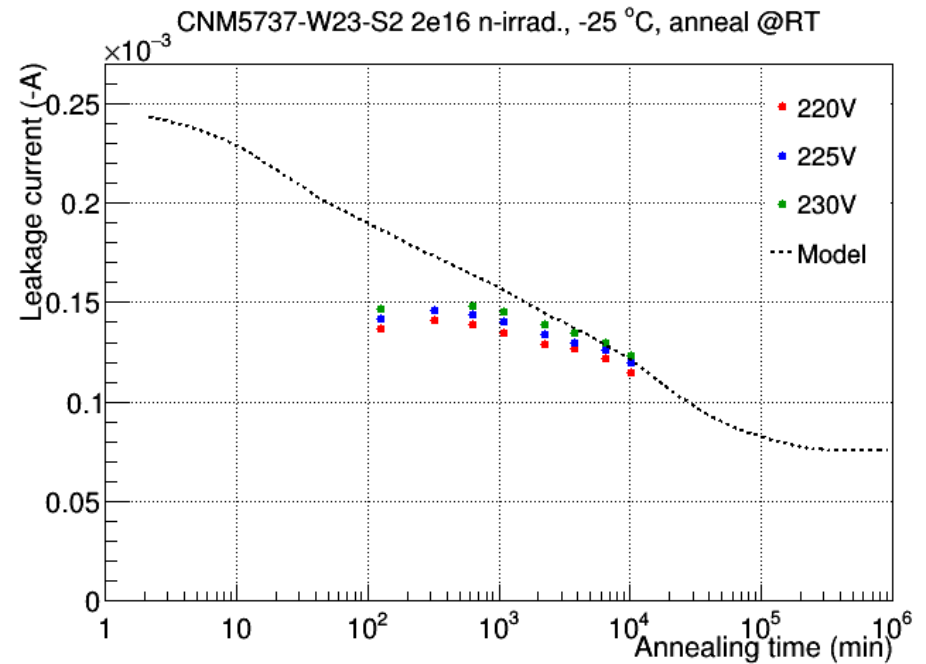
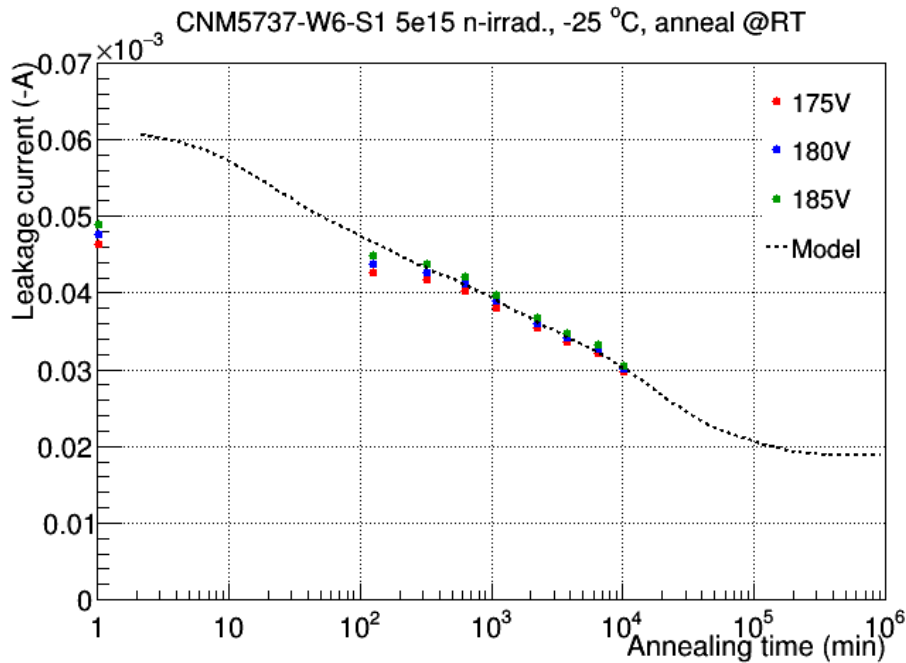
7d@RT anneal., -25 °C



Model by Wunstorf/Moll

- Climate chamber set to -25 °C (chip off)
 - Benchmark T for ATLAS ITk
- Annealing to 7d at room temperature
- Fluence dependence as expected
 - Devices at same fluence agree reasonably
- Definition of operational V_{op}
 - Point where hit efficiency >97%
 - 5e15 n_{eq}/cm^2 : 160 V (IBL beam tests)
 - 1e16 n_{eq}/cm^2 : 180 V (new FEI4 beam tests) (see I. Lopez' talk)
 - 2e16 n_{eq}/cm^2 : 200-250 V
from charge collection: $Q \sim 4$ ke, CCE > 20%
 - Will need less V_{op} for smaller electrode dist. (but possibly some compensation for thinner)
- Current at V_{op} similar to model prediction with $\alpha=4.7e-17$ A/cm

Leakage Current: Annealing

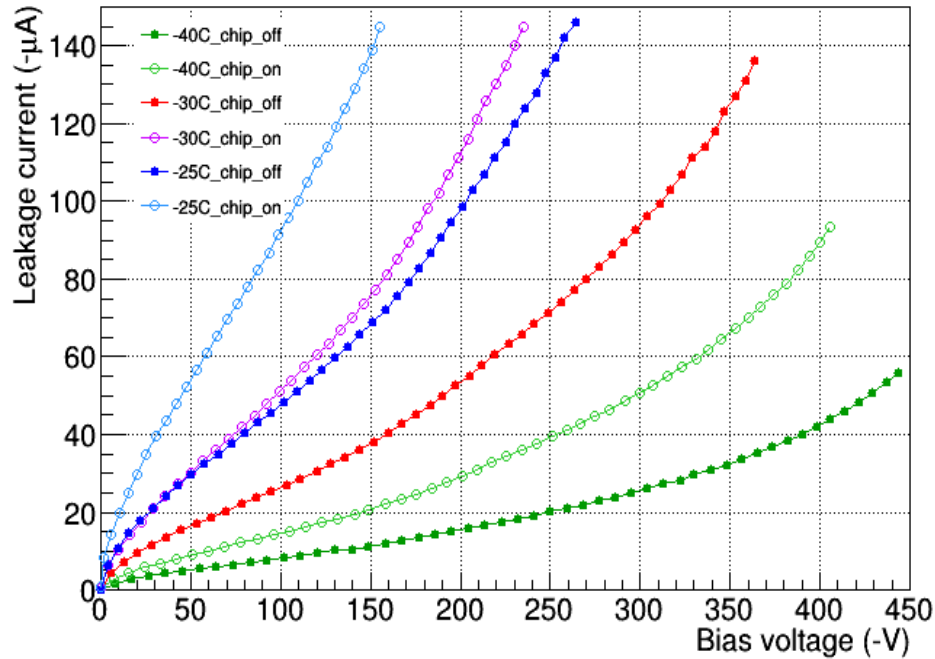


Model by Wunstorf/Moll

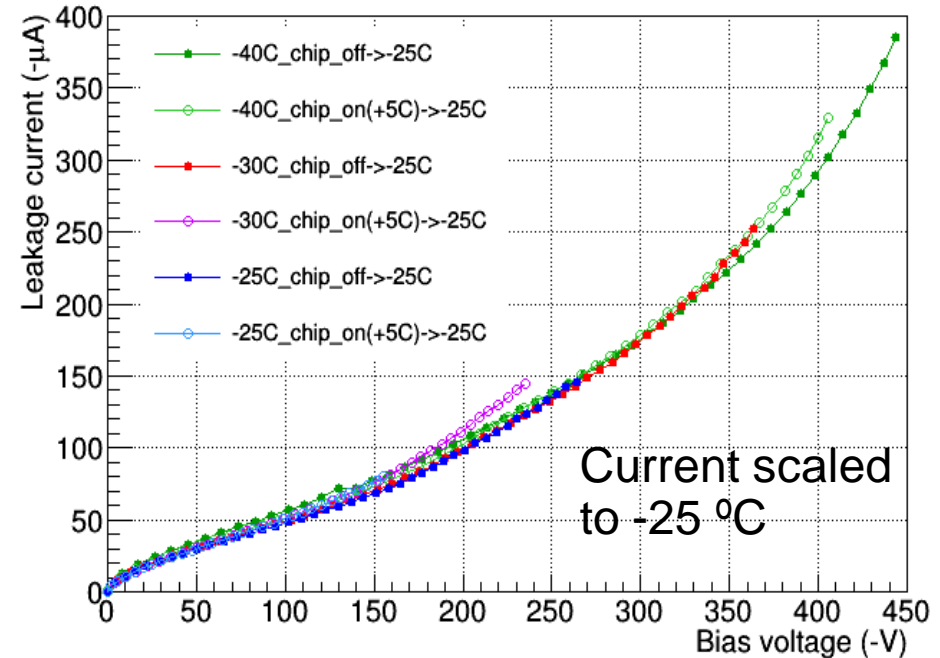
- Current decreases with annealing as expected
 - By $\sim 20\%$ after 1 week at room temperature

Leakage Current: Temperature Dependence

CNM5737-W23-S2 2e16 cm⁻² n-irrad., 7d@RT anneal.



2e16 cm⁻² n-irrad., 7d@RT anneal., scaled to -25 °C



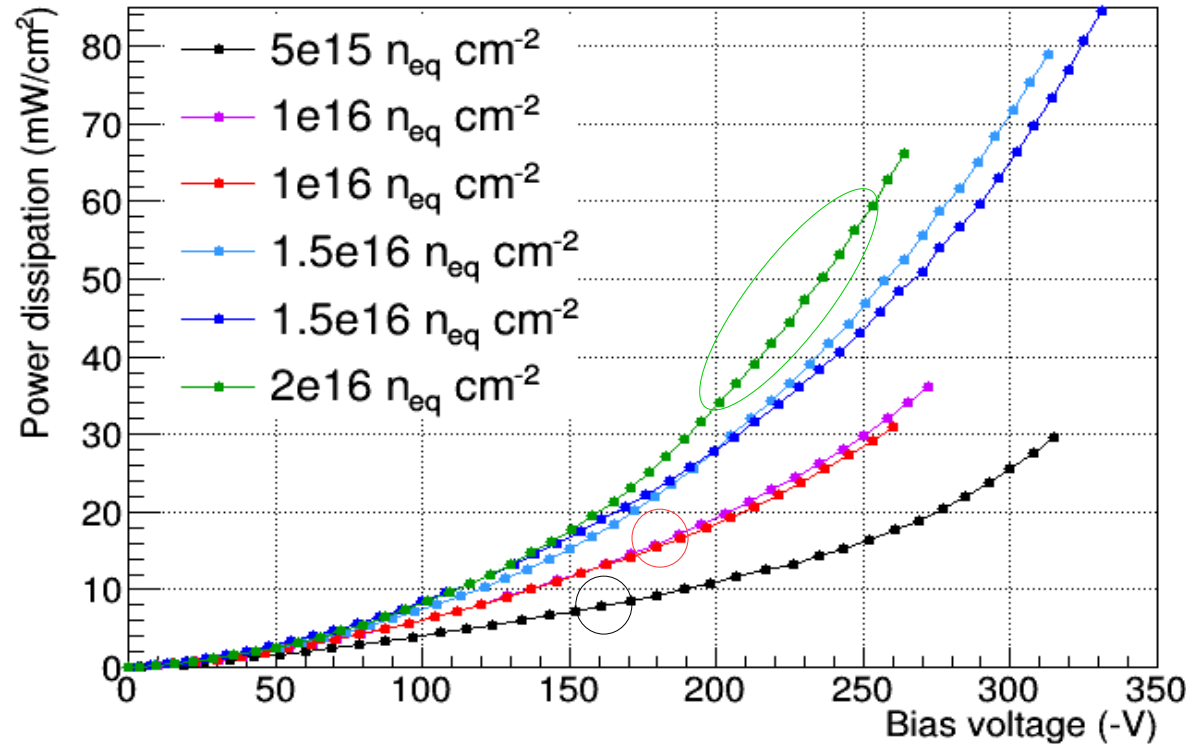
$$\frac{I}{I_0} = \left(\frac{T}{T_0}\right)^2 e^{-\frac{E_g}{2k_B}\left(\frac{1}{T} - \frac{1}{T_0}\right)},$$

where $E_g = 1.2 \text{ eV}$, $k_B = 8.62 \times 10^{-5} \text{ eV/K}$

- Temperature scaling as expected (taking $E_g=1.2 \text{ eV}$)
- Higher current when FEI3 chip is on due to heating up
→ corresponds to T increase by ~5 C

Power Dissipation

7d@RT anneal., -25 °C 230 μm



Fluence (neq/cm ²)	V _{op} (V)	I (uA/cm ²) [230 μm]	I (uA/cm ²) [150 μm]	Power (mW/cm ²) [230 μm]	Power (mW/cm ²) [150 μm]
1E15	50	6	4	0.3	0.2
5E15	160	46	30	7.4	4.8
1E16	180	83	54	14.9	9.7
2E16	200	160	104	32.0	20.8
2E16	250	220	144	55.0	36.0

- Critical parameter for cooling and stove/service design
 - Should be as low as possible
- ATLAS ITk baseline T of -25 C
- **At 1e16 n_{eq}/cm² and V_{op}=180 V**
 - 15 mW/cm² at 230 μm
 - **10 mW/cm²** scaled to ATLAS ITk benchmark thickness of 150 μm (validity of scaling demonstrated on next slides)
- Significantly lower than for planar devices
- For smaller electrode distance → expect lower V_{op} (for same thickness) → improved power dissipation

Compilation of Current and Power Dissipation

Fluence [n _{eq} /cm ²]	V _{op} [V]	Irradiation	Sample	Thick- ness [μm]	Electrode Distance [μm]	Column Diam. [μm]	I/area for 230 μm [μA/cm ²]	P/area for 230 μm [mW/cm ²]
5e15	160	n (Ljubljana)	CNM FEI3 Pixel [1]	230	71	13	46	7.4
		23 MeV p (KIT)	CNM34 FEI4 Pixel [2]	230	67	13	36	5.6
		23 MeV p (KIT)	CNM97 FEI4 Pixel [2]	230	67	13	41	6.6
		23 MeV p (KIT)	FBK11/87 FEI4 Pixel [2]	230	67	11	39	6.1
		n (Ljubljana)	CNM81 FEI4 Pixel [2]	230	67	13	48	7.6
		23 MeV p (KIT)	CNM strip 1 [3]	285	57	13	43	6.8
		23 MeV p (KIT)	CNM strip 2 [4]	285	57	13	44	7.0
		23 MeV p (KIT)	FBK strip [5]	230	57	11	40	6.4
1e16	180	n (Ljubljana)	CNM FEI3 Pixel [1]	230	71	13	83	14.9
		23 MeV p (KIT)	CNM strip 1 [3]	285	57	13	90	16.2
2e16	200	n (Ljubljana)	CNM FEI3 Pixel [1]	230	71	13	160	32.0
		23 MeV p (KIT)	CNM strip 2 [4]	285	57	13	98	19.6
		23 MeV p (KIT)	FBK strip [5]	230	57	11	165	33.0

- Comparison between different 3D devices and irradiations (p, n)
- All values scaled to -25 C, 7d@RT annealing and 230 μm thickness
- Good agreement:** max. 41% deviation per fluence (usually better)
- Thickness scaling works** (between 50 and 285 μm)
- Independent of**
 - Column diameter** (between 6 and 13 μm)
 - Electrode distance** (between 57 and 71 μm)

[1] Measured by IFAE 2015 at -25 C, 7d@RT annealing (this talk)

[2] ATLAS IBL Coll., JINST 7 (2012) P11010, remeasured by IFAE 2015 at -25 C, 120min@60C annealing

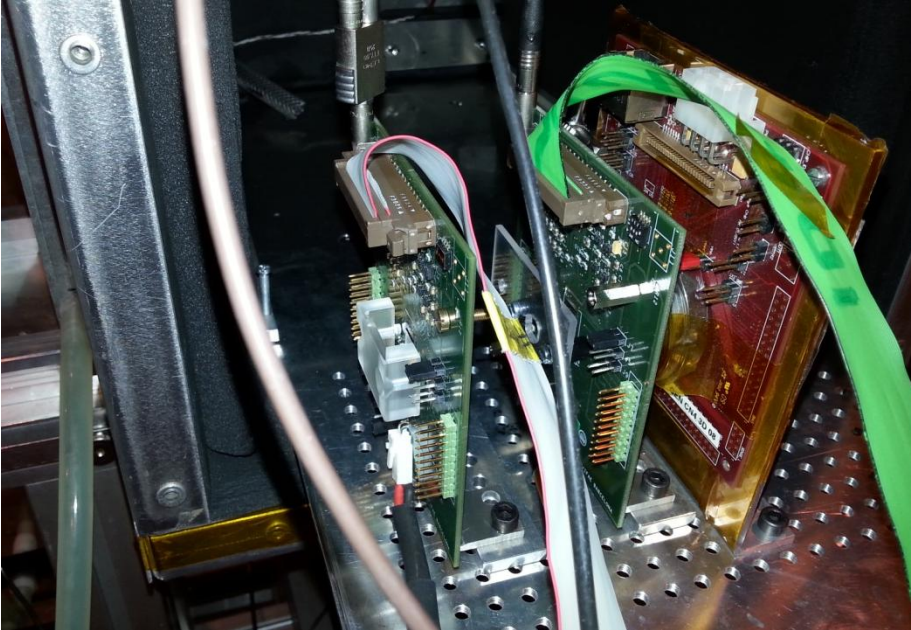
[3] C. Fleta, RD50 Workshop June 2010, measured at -10 C, 1d@RT or 4min@80 C annealing

[4] M. Köhler, PhD thesis Uni Freiburg, 2011, presented at 20 C, few days@RT annealing (not corrected for)

[5] G.F. Dalla Betta et al., NIMA 765 (2014) 155, presented at -20 C, as irradiated (assumed 1d@RT annealing)

[6] G. Pellegrini 27th RD50 workshop + M. Baselga, PhD thesis 2016 (in prep.), measured at -20 C, 8min@80 C annealing

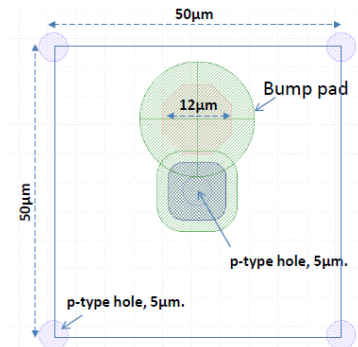
Beam Tests



- Tried to measure FEI3 hit efficiencies in beam tests in July and September
- Not straight forward anymore to operate FEI3 in beam tests with EUDET/AIDA telescopes
 - Seem to be very sensitive to noise and high rate
 - Eventually working
- Took a few runs for $1e16 n_{eq}/cm^2$ FEI3 device
 - Analysis on-going
- More runs planned at next beam tests

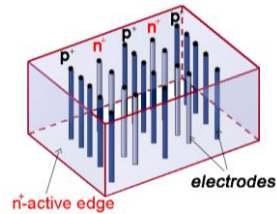
Conclusions

- First time studied 3D pixel detectors up to HL-LHC fluences
 - Here: neutron irradiated FEI3 up to $2e16 n_{eq}/cm^2$
 - Next talk: proton irradiated FEI4 up to $9e15 n_{eq}/cm^2$
- Even IBL/AFP generation of pixel detectors shows good performance
 - MPV ~ 4 ke and CCE $>20\%$ at $2e16 n_{eq}/cm^2$ for 2.5 ke FEI3 threshold
→ expected to improve significantly at 1 ke HL-LHC threshold and 35 μm electrode distance
 - Leakage current at V_{op} close to model expectations from bulk current
 - Excellent power dissipation:
15 (10) mW/cm 2 at $1e16 n_{eq}/cm^2$ for 230 (150) μm thickness and -25 C
- New 3D production runs on-going
 - Smaller pixel size and electrode distance, thinner, smaller columns
→ expect improved performance
 - First results expected early next year

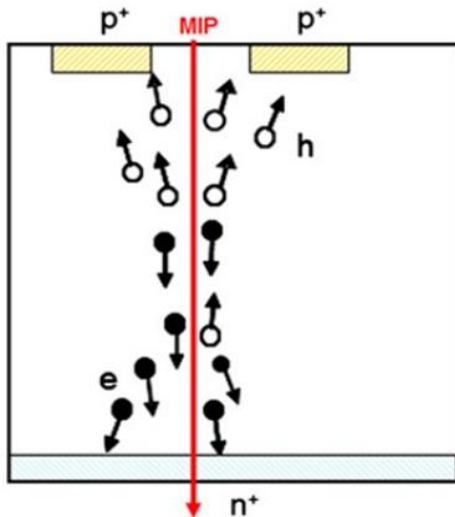


BACKUP

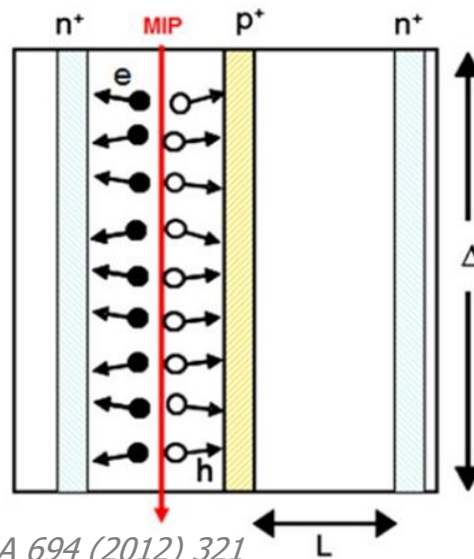
3D Detector Principle



Planar Technology



3D Technology



C. Da Via et al., NIM A 694 (2012) 321

Radiation-hard and active/slim-edge technology

Advantages

- Electrode distance decoupled from sensitive detector thickness
 - lower $V_{\text{depletion}}$
 - less power dissipation, cooling
 - smaller drift distance
 - faster charge collection
 - less trapping
- Active or slim edges are natural feature of 3D technology

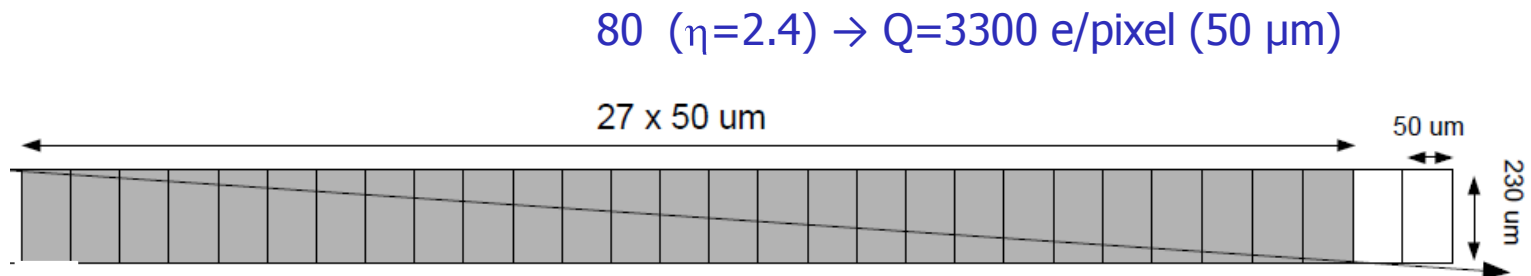
Challenges

- Complex production process
 - long production time
 - lower yields
 - higher costs
- Higher capacitance
 - higher noise
- Non-uniform response from 3D columns and low-field regions
 - small efficiency loss at 0

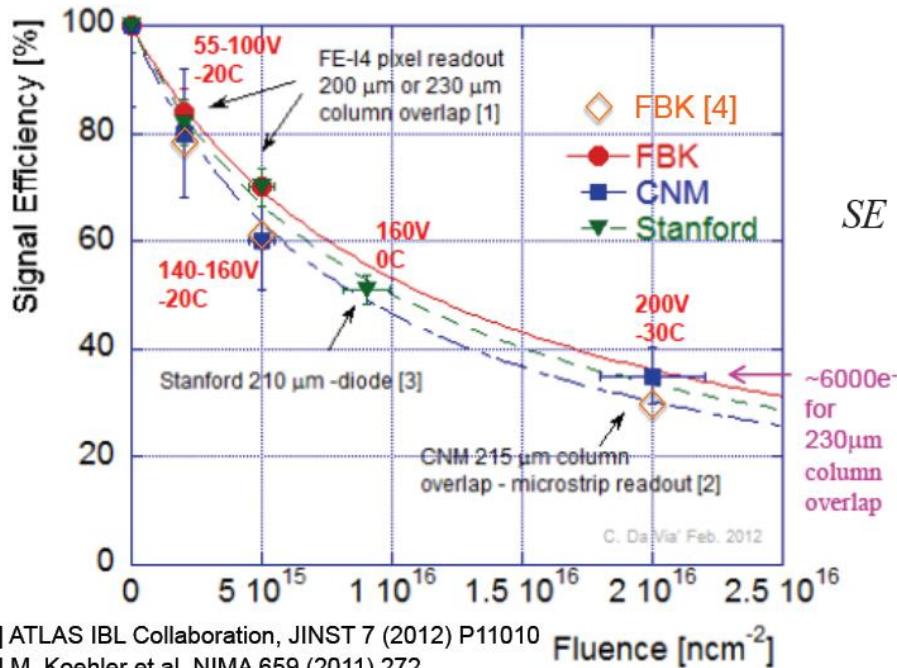
HL-LHC Studies: High Eta

- Large clusters \rightarrow large total charge \rightarrow efficiency for whole cluster not a problem
- But for 50 μm pitch very small charge deposition per pixel (almost parallel tracks): 3300 e
- Testbeam campaign to measure CNM+FBK IBL FE-I4 devices with 80° angle in short pitch direction (50 μm)
 - 1000 + 1500 e threshold
 - Cluster size 24-27
 - >99% efficiency per pixel before irradiation

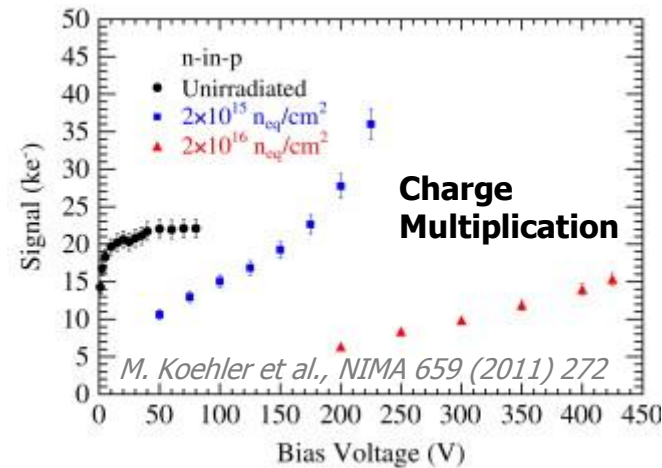
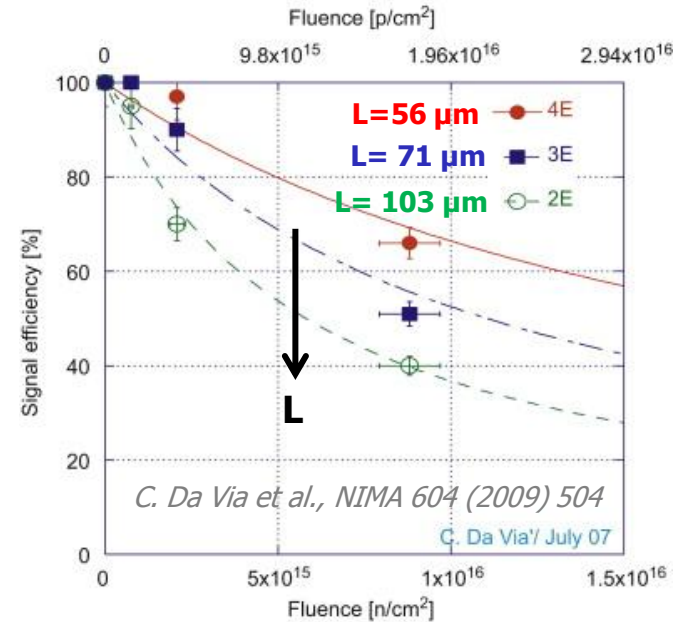
See talk by Ivan Lopez



R&D Performance Summary



$$SE = \frac{1}{1 + 0.6L \frac{K_L}{v_D} \Phi}$$



- [1] ATLAS IBL Collaboration, JINST 7 (2012) P11010
- [2] M. Koehler et al. NIMA 659 (2011) 272
- [3] C. Da Via, et al., NIMA 604 (2009) 505
- [4] G.-F. Dalla Betta, et al., HSTD9 (2013)

Compilation by C. Da Via, modified by G.F. Dalla Betta

- Signal efficiency (SE) of 60-70% at $5 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$ and 30% at $2 \times 10^{16} \text{ n}_{\text{eq}}/\text{cm}^2$ achieved for moderate $V < 200 \text{ V}$
- Signal efficiency (SE) improves with decreasing electrode distance L
- Charge multiplication at high fluences and V can further boost collected charge